

Notice of References Cited	Application/Control No. 10/601,124	Applicant(s)/Patent Under Reexamination CHEN, ZHONG-WEI	
	Examiner Jack I. Berman	Art Unit 2881	Page 1 of 1

U.S. PATENT DOCUMENTS

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
	A	US-6,392,231	05-2002	Chen, Zhong-Wei	250/310
	B	US-			
	C	US-			
	D	US-			
	E	US-			
	F	US-			
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	I	US-			
	J	US-			
	K	US-			
	L	US-			
	M	US-			

FOREIGN PATENT DOCUMENTS

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	N					
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NON-PATENT DOCUMENTS

*		Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages)
*	U	Chen et al., "The optical properties of "Swinging Objective Lens" in a combined magnetic lens and deflection system with superimposed field", Optik, Vol. 64, No. 4 (1983), pp.341-347.
*	V	Chen et al., "Nanowriter: A new high-voltage electron beam lithography system for nanometer-scale fabrication", Journal of Vacuum Science and Technology B, Vol. 6, No. 6 (Nov/Dec 1988), pp. 2009-2013.
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	X	

*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)
Dates in MM-YYYY format are publication dates. Classifications may be US or foreign.